

Enquiry No: ME/KKK/03-2011-12

Dated: December 07, 2011

http://www.iitk.ac.in/infocell/tender/file/ME_KKK_03_2011_12 Enquiry.pdf

Sealed Quotation must reach to us till 25.12.2011 before 5.00PM and should be sent to Kamal K. Kar, Mech Engg Dept, IIT Kanpur.

The quotations submitted against the enquiry letter numbered ME/KKK/03-2011-12 and the present one will be opened on 27.12.2011.

Dear Sir/Madam:

Quotations are invited for purchase of "PECVD" having following specifications:

SPECIFICATIONS:

1. Substrate temperature: 900°C (minimum), 1000° C (preferable) (if it is 1100° C, extra advantage)
2. Vacuum: 10⁻⁷ torr
3. Power supply: high frequency 600W NM Inductively coupled Plasma (preferable), if not available then 600 W RF Plasma
4. Mass flow controllers: five for gases (one silane) and another two for liquid precursors (total seven mass flow controllers)
5. Substrate size: 2 inch (minimum)
6. Plasma cleaning: Yes
7. Silane cleaning: Yes
8. RF Shower head or HCD plasma

Applications: not specific

Terms & Conditions:

1. Prices should be on FOB and CIF (IIT-Kanpur)
2. Prices should include the installation and training cost.
3. Warranty should at least be for three years after installation.
4. Validity of quotation should be at least for 60 days
5. Quotation should carry proper certifications like agency certificate, proprietary certificate, etc
6. Maximum educational discount, if any
7. Any other charges from your side (Freight, Insurance, etc)

Kindly mention "PECVD" (ME/KKK/03-2011-12)" on sealed envelope carrying quotation and printed literature and send your best offer (Technical & Commercial) so as to reach us on or before December 25, 2011 to the following address-

Dr. Kamal K. Kar

Department of Mechanical Engineering
IIT Kanpur - 208016 India

Email: Kamalkk@iitk.ac.in